



제 31회 한국반도체학술대회

The 31st Korean Conference on Semiconductors

2024년 1월 24일(수)-26일(금) | 경주화백컨벤션센터(HICO)

2024년 1월 25일(목), 09:00-10:45

Room L(206), 2층

Q. Metrology, Inspection, Analysis, and Yield Enhancement 분과

[TL1-Q] Metrology, Inspection, and Yield Enhancement I

좌장: 강상우 소장(한국표준과학연구원), 정용우 TL(SK hynix)

초청발표 TL1-Q-1 09:00-09:30	SEM 영상을 활용한 패턴의 3차원 측정 방법 Younghoon Sohn Samsung Electronics Co., Ltd.
초청발표 TL1-Q-2 09:30-10:00	Skyrmionics Chanyong Hwang KRISS
TL1-Q-3 10:00-10:15	Metrology/Inspection System of Extra Ultraviolet (EUV) Material and Optical Components for Ultra-fine Semiconductor Patterning Wooram Kim ¹ , Eun Seok Choe ¹ , Do-Yeon Hwang ¹ , Hyo-Chang Lee ^{1,2} , Jung-Hyung Kim ¹ , Won Chegal ¹ , and Sang-Woo Kang ¹ ¹ Semiconductor Integrated Metrology Team, KRISS, ² Department of Electronics and Information Engineering, Korea Aerospace University
TL1-Q-4 10:15-10:30	The Study of Optical Measurement Technologies for the Advanced Packaging of the Semiconductor Manufacturing Process Joon Ho You and Chang Soo Kim Nexensor Inc.
TL1-Q-5 10:30-10:45	Development of ARDE Technology for HARC Using IEDF based on High-resolution VSEM Etch Profile Data Jihoon Park ¹ , Namjae Bae ¹ , Ji-Won Kwon ¹ , Taejun Park ¹ , Jaemin Song ² , and Gon-Ho Kim ¹ ¹ Seoul National University, ² Samsung Electronics Co., Ltd.